

Electronic Acknowledgement Receipt

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Application Number:	09972608
International Application Number:	
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Title of Invention:	METHOD FOR THE PRODUCTION OF LOW DEFECT DENSITY SILICON
First Named Inventor/Applicant Name:	Vladimir V. Voronkov
Customer Number:	321
Filer:	Richard A. Schuth/Lori Macke
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File Listing:

Document Number	Document Description	File Name	File Size(Bytes)	Multi Part /.zip	Pages (if appl.)
1	Miscellaneous Incoming Letter	COCLPTO.PDF	27455	no	1

Warnings:

Information:	
Total Files Size (in bytes):	27455
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